

2818 #

**COMBINED AMENDMENT & PETITION FOR EXTENSION OF
TIME UNDER 37 CFR 1.136(a) (Large Entity)**

Docket No. ☒
OKI.291

In Re Application Of: **Yoshirou Tsurugida**

Serial No.
10/034,379

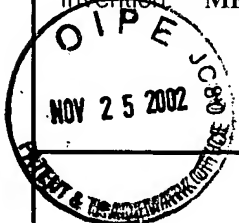
Filing Date
01/03/2002

Examiner
NHU, DAVID

Group Art Unit
2818

5/1/04
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DEC-2 2002
TECHNOLOGY CENTER-2800

Invention: **METHOD FOR SELECTIVELY OXIDIZING A SILICON WAFER**



TO THE ASSISTANT COMMISSIONER FOR PATENTS:

This is a combined amendment and petition under the provisions of 37 CFR 1.136(a) to extend the period for filing a response to the Office Action of 06/25/02 in the above-identified application.
Date

The requested extension is as follows (check time period desired):

☐ One month ☒ Two months ☐ Three months ☐ Four months ☐ Five months

from: 09/25/02 until: 11/25/02
Date *Date*

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The fee for the amendment and extension of time has been calculated as shown below:

CLAIMS AS AMENDED

	CLAIMS REMAINING AFTER AMENDMENT	HIGHEST # PREV. PAID FOR	NUMBER EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	7 -	20 =	0	x \$18.00	\$0.00
INDEP. CLAIMS	1 -	3 =	0	x \$84.00	\$0.00
FEE FOR AMENDMENT					\$0.00
FEE FOR EXTENSION OF TIME					\$400.00
TOTAL FEE FOR AMENDMENT AND EXTENSION OF TIME					\$400.00

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Serial No. 10/034,379
OKI.29T

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent application of :
Yoshirou Tsurugida : Group Art Unit 2818
Serial No. ¹⁰~~09~~7034,379 : Examiner David Nhu
Filed January 3, 2002 :
METHOD FOR SELECTIVELY OXIDIZING A SILICON WAFER

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AMENDMENT

Honorable Commissioner For Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated June 25, 2002, the period for
response having been extended by a concurrently filed Petition For Extension Of
Time, the following amendments and remarks are submitted:

In the Specification¹

*Kindly rewrite the paragraph bridging pages 4-5 of the specification to
read as follows:*

a1 Figs. 1(A) through 1(E) show process steps of a selective oxidation method
according to the present invention.

¹ A copy of any revised paragraphs/sections of the specification is attached at ATTACHMENT
"A".